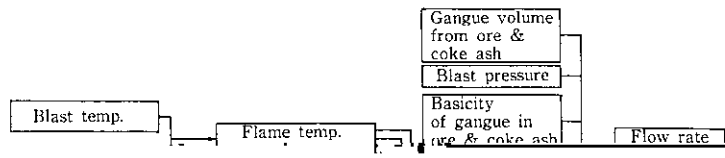


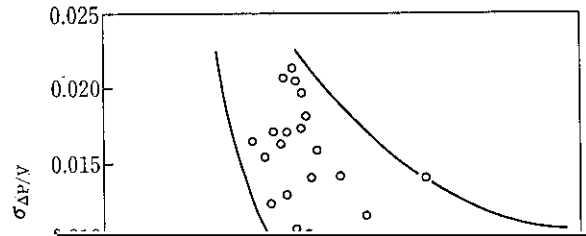
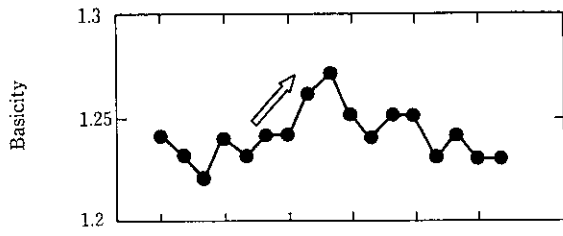


# Low-Silicon Operation of Blast Furnace

## 要旨

山崎製鉄株式会社 昭和三十三年三月





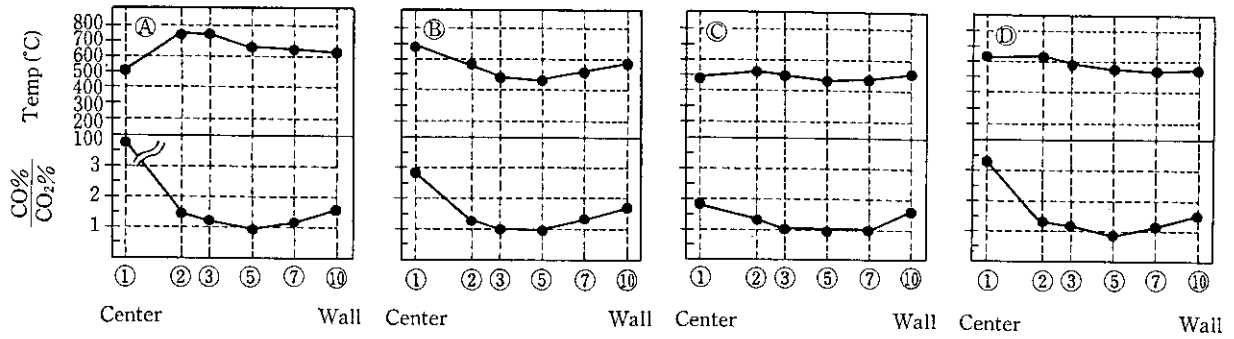
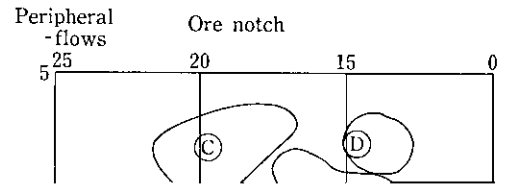
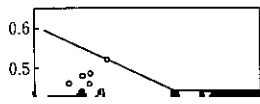


Fig. 6 Change of gas distribution by shaft probe

$$\frac{\frac{\sigma_{AP}/V}{AP}}{V}$$

およびガス変動値 (炉頂ガスの利用率 CO vol%/CO<sub>2</sub> vol% の変動値)

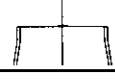
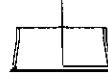




'82/11

'83/12

'84/6



0.40

37